



U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/035,829
	Filing Date: 10/18/2001
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventors: Vlad J. Novotny and Parvinder Dhillon
"Multi-Axis Micro-Electro-Mechanical Actuator"	Group Art Unit: 2874
	Examiner Name: Stahl, Michael J.
	Attorney Docket No.: AO-666

## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
MJS	A	6,580,846 B1	06/17/03	Burroughs et al.	385	16	
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						

Examiner M. Stahl

Date Considered

7/10/04

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/035,829
	Filing Date: 10/18/2001
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor: Vlad J. Novotny
"Micro-Electro-Mechanical Switching System"	Group Art Unit: 2874
	Examiner Name: Stahl, Michael J.
	Attorney Docket No.: AO-666 AONIP001C1

U.S. Patent / Patent Publication Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
MJS	A	6,028,689	02/22/00	Michalicek et al.	359	224	
MJS	B	6,253,001 B1	06/26/01	Hoen	385	17	
MJS	C	6,283,601 B1	09/04/01	Hagelin et al.	359	871	
MJS	D	6,301,403 B1	10/09/01	Heanue et al.	385	18	
MJS	E	US 2002/0171327 A1	11/21/02	Miller et al.	310	309	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

MJS	F	ELWENSPOEK, M. et al., "Silicon Micromachining." 1998 - Cambridge University Press. Cover page, pages 102-111, pages 160-161 and page 282.					
MJS	G	MALUF, NADIM, "An Introduction to Microelectromechanical Systems Engineering." 2000. Cover page, pages 6464-73 and pages 186-189.					
MJS	H	RAI-CHOUDHURY, P., "Handbook of Microlithography, Micromachining, and Microfabrication." 1997 - SPIE Optical Engineering Press. Pages 110-116 and pages 120-122.					
MJS	I	CONANT, ROBERT A. et al., "A Flat High-Frequency Scanning Micromirror." 2000 - Solid-State Sensor & Actuator Workshop, Hilton Head, SC.					
MJS	J	BEZUK, STEVE, PH.D., "Flip Chip Challenges." 02/00 - HD Magazine. 6 pages.					
MJS	K	CHEN, YIJIAN, "Control and Shape Design of an Electrically-Damped Comb Drive for Digital Switches." 2000 - MOEMS and Miniaturized Systems. Proceedings of SPIE Vol. 4178. Pages 387-394.					
MJS	L	DAWSON, J.M. et al., "MEMS Feedback Control Using Through-Wafer Optical Device Monitoring." September 2000 - Proc. Of SPIE Vol. 4178, MOEMS and Miniaturized Systems.					

Examiner M. Stahl

Date Considered 7/10/04

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/035,829
	Filing Date: 10/18/2001
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor: Vlad J. Novotny
"Micro-Electro-Mechanical Switching System"	Group Art Unit: 2874
	Examiner Name: Stahl, Michael J.
	Attorney Docket No.: AO-666 AONIP001C1

U.S. Patent / Patent Publication Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
	M						
	N						
	O						
	P						
	Q						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

MJS	R	LEE, SANGWOO, et al., "The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon." December 1999. Journal of Microelectromechanical Systems, Vol. 8, No. 4. Pages 409-416.					
MJS	S	MILANOVIC, VELJKO, "Optical MEMS for Optical Communications - Trends and Developments." 12/01. Adriatic Research Institute. Pages 2-6.					
MJS	T	NEE, JOCELYN T. et al., "Lightwave, Optically Flat Micromirrors for Fast Beam Steering." Presented at IEEE/LEOS Optical MEMS August 2000 Conference in Kauai, Hawaii. 2 pages.					
MJS	U	TIEN, NORMAN C. et al., "MEMS Actuators for Silicon Micro-Optical Elements." 2000 - Proceedings of SPIE Vol. 4178. Pages 256-267.					
	V						
	W						
	X						

Examiner M. Stahl

Date Considered 7/10/04

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.